

Spectrum® 3013 3.0 kW 13.56 MHz 3U Half Rack RF Generator

Spectrum[®] RF Plasma Generator

13.56 MHZ MODEL 3013 AND 1513

Spectrum[®] generators feature high power density, excellent stability, generous power margins and high reliability for lower cost of ownership and improved yield, wafer-to-wafer and run-to-run. The Spectrum RF generator is available in power levels of 3.0 and 1.5kW at 13.56MHz.

The Spectrum RF Plasma Generator is used in Chemical Vapor Deposition (CVD), Physical Vapor Deposition (PVD), etching and other thin film applications during the manufacture of integrated circuits, flat panel displays, optical media and industrial coatings.

Features & Benefits

High Repeatability for Consistent Process Performance

- Forward Power Accuracy of ±1.0% of set point, tied to and transferable from NIST
- 500µsec response to power set point changes and process step transitions for improved uniformity

Smaller Footprint Reduces Required Tool Space

- Power density increased 2-3 times over previous models
- Integrated auto frequency tuning eliminates the need for a complex matching network

High Reliability Increases Uptime and Lowers CoO

- Improved thermal management and decreased power dissipation through the use of new, high efficiency power amplifier (PA)
- Push-pull resonant circuit topology lowers the voltages across the power transistors
- Ample power margin allows more forward power delivery and more strike voltage potential to bridge sub-optimal conditions with no process interruption

Powe ≶ ≶ ≶ \leq ス ഗ Z ഗ -C

0

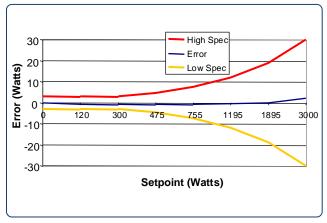
<

Spectrum[®] RF Generator Performance

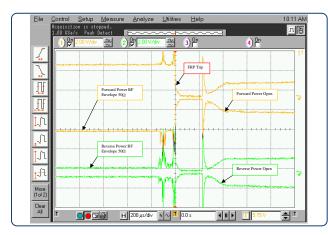
The Spectrum platform combines high performance specifications with a flexible, reliable design. The result is a robust platform for the most demanding thin film applications.

Accuracy

The Spectrum generator leads the industry with accuracy of $\pm 1.0\%$ of Forward Power tied to and transferable from the National Institute of Standards and Technology. High accuracy ensures tight process control and repeatability for advanced thin film processing.



Spectrum Generator Forward Power Accuracy vs Output Power



Plot of drain source voltage and modulator detection and response at 200 microseconds per division

RF Power Margin

A key indicator of reliability is headroom or RF power margin. Having extra RF power capability ensures high performance, uptime and yield under difficult process conditions. RF power margin allows more forward power delivery into mismatched loads. On hard to ignite chambers, headroom provides more strike voltage potential. During conditions of lower line voltage, RF power margin allows full rated power to be delivered instead of de-rating the generator.



Spectrum RF Generator Power Margin

Automatic Frequency Tuning (AFT)

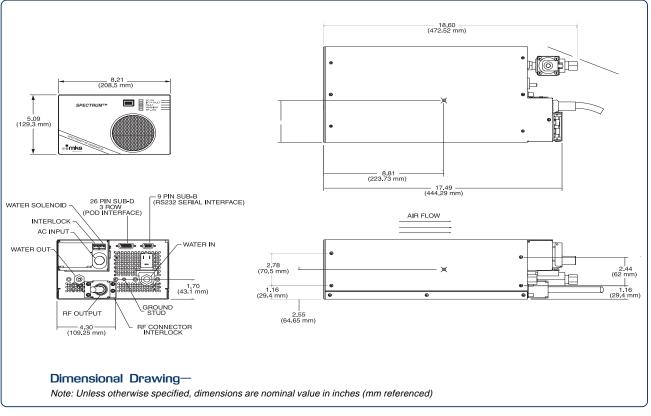
The Spectrum RF plasma generator incorporates automatic frequency tuning-impedance matching which eliminates the need for a complex matching network. AFT automatically locates the best operating frequency for optimal power transfer. The 13.56 MHz Spectrum generator is capable of tuning to \pm 5%.

Fast Transient Recovery

When an arc occurs within the plasma, the RF drive is quickly and momentarily shut off to the PA, thus preventing disruption of the process and damage to the generator, matching network, chamber or substrate. The generator will detect, react, and recover without any action needed from the user. Detection is typically within 5μ S while react and recover timeframe is adjustable from 40μ S to 4mS.

Safety and Performance

The Spectrum generator will shut down with a fault indication under the following conditions: Internal Temperature, Heatsink Temperature, Interlock Interrupt, or if any monitored circuit parameters reach a hazardous level. A warning indicator is provided to communicate a condition approaching the fault levels, as listed above, or conditions of line voltage out of range, high humidity, or condensation. This allows action to be taken before a fault would occur. Water flow is controlled to prevent condensation and is based on heatsink temperature and relative humidity.



Spectrum 3013 3U Half Rack

Specifications and Ordering Information

Parameter	Model #3013-00	Model #1513-00
Frequency Center (MHz)	13.56 ±0.005%	
Auto Frequency Tuning (bandwidth)	±5%	
Dynamic Power Range	30W - 3000W	30W - 1500W
Load Regulation (worst phase forward power) W nominal into 1.1:1 VSWR W nominal into 1.5:1 VSWR W nominal into 2.0:1 VSWR W nominal into 3.0:1 VSWR W nominal into ∞:1 VSWR Load Transient Recovery	3000W 3000W 2400W 1700W 600W Forward power shuts down in appr	1500W 1500W 1500W 1500W 600W roximately 5 microseconds if reverse power
	exceeds preset threshold (normally twice the steady-state reverse limit). Recovery period is adjustable from 200 microseconds (default) to 1.2 milliseconds	
Load Impedance Range	Unlimited	
RF Stability Spurious Output	Unconditionally stable for any load within operational limits < 50dBc into 50 ohm load	
Harmonic Output/Distortion	< 40dBc, Maximum (50 ohm load)	
Software Pulsing Parameters Frequency Minimum Pulse Width RF Rise/Fall Time	0-1kHz 500μsec 150μsec	
Power Control Accuracy ¹ ± 1% of Set Point ± 1% of Full Scale	>300W <300W	
Interface Standard Optional Dimensions H x W x D inches (mm) Weight lbs (kg)	RS232, subminiature 9-pin Type DB9F; Versatile Monitor Interface External: 25 pin Analog, or DeviceNet [™] or Profibus [®] 1.4 x 5.6 x 3.7 (36 x 142 x 94) 1.1 (0.5)	
Generator Dimensions ² H x W x D inches (mm) U	5.25 x 8.2 x 17.5 (133 x 208 x 444) 3 U, Half Rack	
Generator Weight (maximum)	38 lbs (17 kg)	
Facility Requirements Primary AC Power Source Rated Current Circuit Breaker Ambient Temperature Cooling Water (minimum)	200/208 VAC ±10% 3 Phase 20A 25A +5 to +35°C, non condensing 1.5 gpm (5.7 lpm)	
Compliance	CE to EMC 89/336/EEC and LVD 72/23/EEC; SEMI F-47; NRTL Listed	
RF Output Connector ³ Type QC Flange	HN	

¹ Subject to limits of Forward and Reverse Power, Current and Voltage

² Excludes handles and connectors

³ Standard, others available, user configurable

Please contact your local MKS office for price and availability.



SpectrumRF - 1/08 © 2005 MKS Instruments, Inc. All rights reserved.

Global Headquarters

2 Tech Drive, Suite 201 Andover, MA 01810 Tel: 978.645.5500 Tel: 800.227.8766 (in U.S.A.) Web: www.mksinst.com

Power Generators & Subsystems

100 Highpower Road Rochester, NY 14623 Tel: 585.427.8300

Specifications are subject to change without notice. Spectrum[®] is a registered trademark of MKS Instruments, Inc., Andover, MA. DeviceNet[™] is a trademark of the Open DeviceNet Vendor Association, Coral Springs, FL. Profibus[®] is a registered trademark of Profibus International.